

Title (en)

PIEZOELECTRIC MICRO-SYSTEM FOR THE ACTIVE VIBRATORY INSULATION OF VIBRATION SENSITIVE COMPONENTS

Title (de)

PIEZOELEKTRISCHES MIKROSYSTEM ZUR AKTIVEN SCHWINGUNGSISOLIERUNG VON SCHWINGUNGSEMPFINDLICHEN KOMPONENTEN

Title (fr)

MICROSYSTÈME PIÉZOÉLECTRIQUE POUR L'ISOLATION VIBRATOIRE ACTIVE DE COMPOSANTS SENSIBLES AUX VIBRATIONS

Publication

EP 2018347 A1 20090128 (FR)

Application

EP 07731337 A 20070420

Priority

- FR 2007000676 W 20070420
- FR 0603494 A 20060420

Abstract (en)

[origin: WO2007122330A1] Micro-system for active vibratory insulation, characterised in that it comprises a stand which includes a frame (1) and at least two beams (2a, 2b) which interlock and carry or are intended to carry an element requiring stabilisation (3), said beams (2a, 2b) carry at least one piezoelectric layer (4a, 4b, 4c) and electrodes which define different piezoelectric areas, at least two (4a, 4c) of which are piezoelectric measurement areas, sensitive to the distortions of the beam or beams which carry them, and at least one (4b) of which is a piezoelectric activation area, controlled as a function of the output signals of the piezoelectric measurement areas according to a stabilisation control law.

IPC 8 full level

B81B 7/02 (2006.01); **H02N 2/00** (2006.01)

CPC (source: EP)

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Citation (search report)

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DOCDB simple family (publication)

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